

L Number	Hits	Search Text	DB	Time stamp
2	149359	sputter\$3	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2002/11/06 10:06
9	21292	prevent adj contamination	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2002/11/06 10:07
16	1056	sputter\$3 and (prevent adj contamination) and (aluminum or al)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2002/11/06 10:07
23	25	sputter\$3 same (prevent adj contamination) same (aluminum or al)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2002/11/06 10:12
30	5	(sputter\$3 with (aluminum or al)) and ((prevent adj contamination) same (coat\$3 with (chamber or wall)))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2002/11/06 10:13

L Number	Hits	Search Text	DB	Time stamp
2	35605	(wafer or substrate) with (pedestal or lifter or holder)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2002/11/06 08:28
9	6205	((pin or support or finger) same ((wafer or substrate) with (pedestal or lifter or holder)))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2002/11/06 08:29
16	10035	(self-centering) or (self adj centering)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2002/11/06 08:29
23	5	((pin or support or finger) same ((wafer or substrate) with (pedestal or lifter or holder))) same ((self-centering) or (self adj centering))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB	2002/11/06 08:29